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For 10/724 535 included herein:

Information Disclosure Cover Letter

Certificate of mailing dated Apr 7, 2004

PTO Form 1449

Copies of cited Art



PATENT

In The United States Patents and Trademark Office

In the application of:
Charles J. Molnar

Case number: **1FALL112903**

Application no.: **10/724535**

Group art: **3723**

Filed: **11/29/03**

Examiner: **Anthony Ojini**

For: **In situ finishing aid control**

Date: 4-7-04

Information Disclosure Statement

Mail Stop DD
Commissioner for Patents
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Sir:

In compliance with 37 CFR 1.56, 1.97, and 1.98, Applicants bring to the attention of the U. S. Patent and trademark Office information listed in the enclosed PTO-1449. A copy of the information is also enclosed.

Applicant, for convenience of PTO, lists pending and / or published applications for consideration:

Application Number	Filing date	Related publication / patent
09/435,181	11-5-99	6,283,829
09/434,723	11-5-99	6,267,644
09/434,722	11-5-99	6,293,851
09/434,724	11-5-99	
09/435,180	11-5-99	6,204,181 with drawn from issue
09/533,473	3-23-00	6,346,202
09/533,846	3-23-00	6,291,349
09/538,409	3-29-00	6,568,989
09/766,958	1-22-01	6,634,927
09/840,423	4-23-01	6,641,463
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09/939,957	8-27-01	
09/954,394	9-17-01	
09/956,687	9-20-01	
10/211,796	8-3-02	

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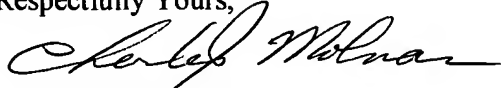
9-30-02

10/724,535

11-29-03

Application with serial number 09/435180 has been published with number 6,204,181 B1.

Very Respectfully Yours,

A handwritten signature in cursive script, appearing to read "Charles J. Molnar".

Charles J. Molnar

12 Malvern Ct., Devon
Wilmington, De 19810
1-302-478-5573

Form PTO-1449 (modified by applicant)	Dock. #: 1FALL112903	Applic #: 10/724535
Information disclosure citation in an application	Filing Date: 12/29/03	Group art unit: 3723
Applicants: Charles J. Molnar/		

US Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
	6298470	8-2-2001	Breiner et al.	716	4	
	6293851	9-25-01	Molnar	451	41	
	6291349	9-18-01	Molnar	438	609	
	6283829	9-4-01	Molnar	451	8	
	6268641	7-31-01	Yano et al.	257	260	
	6267644	7-31-01	Molnar	451	41	
	6263255	7-17-01	Tan et al.	700	121	
	6257953 b1	7-10-01	Gittis et al.	451	5	
	6197604 B1	3-6-01	Miller	438	14	
	6121143	9-19-00	Messner et al.	438	692	
	5993298	11-30-99	Duescher	451	56	
	5985045	11-16-99	Kobayashi	148	240	
	5972793	10-26-99	Tseng	438	692	
	5968280	10-19-99	Ronay	134	2	
	5958794	9-28-99	Bruxvoort	438	692	
	5954997	9-21-99	Kaufman	252	79.1	
	5954975	9-21-99	Cadien	216	38	
	5945347	8-31-99	Wright	438	692	
	5934978	8-31-99	Burke	451	A36	
	5919082	7-6-99	Walker	451	41	
	5916855	6-29-99	Avanzino	51	307	
	5910041	6-8-99	Duescher	451	28	
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	5885334	3-23-99	Suzuki	438	639	
	5885137	3-23-99	Ploessl	106	3	

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Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
	WO 99/64527	12-16-99	Sachan et al.	C09G	1/02	
	WO 98/08919	3-5-98	Kalota et al.	C10M	A2	
	WO 00/00567	1-6-00	Kaufman et al.	C09K	3/14	
	WO 00/00561	1-6-00	Kaufman et al.	C09G	1/02	

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	6204181 withdrawn from issue, Molnar, filed 11-5-99, published March 20, 2001, serial number 09/438180
	BERMAN, MIKE et al., "Review of in Situ and in Line Detection for CMP Applic.", Semiconductor Fabtech, 8 th edition, pp. 267-274.
	BIBBY, THOMAS, "Endpoint Detection for CMP", Journal of Electronic Materials, Vol. 27, #10, 1998, pp. 1073-1081.

Examiner:	Date considered:
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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	5876490	3-2-99	Ronay	106	3	
	5876266	3-1-99	Miller	451	56	
	5860847	1-19-99	Sakurai et al.	451	10	
	5858813	1-12-99	Scherber	438	693	
	5842909	12-1-98	Sandhu	451	7	
	5833519	11-10-98	Moore	451	56	
	5830280	11-3-98	Sato	134	2	
	5783489	7-21-98	Kaufman	438	692	
	5762537	6-9-98	Sandhu	451	7	
	5759917	6-2-98	Grover et al.	438	690	
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	5740033	4-14-98	Wassick et al.	364	149	
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	5735036	4-7-98	Barr	29	603.12	
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	5733176	3-31-98	Robinson	451	41	
	5728308	3-17-98	Muroyama	216	88	
	5722879	3-3-98	Cronin	451	281	
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	5695384	12-9-97	Beratan	451	28	
	5691895	11-25-97	Kurtzberg et al.	364	148	
	5685766	11-11-97	Mattingly	451	36	
	5667629	9-16-97	Pan	438	13	
	5647952	7-15-97	Chen	156	636.1	
	5643060	7-1-97	Sandhu	451	285	
	5639388	6-17-97	Kimura	216	84	
	5614444	3-25-97	Farkas	437	225	
	5609517	3-11-97	Lofaro	451	529	
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Other documents (including Author, Title, Date, Pertinent pages, etc.)

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Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
	5352277	10-24-94	Sasaki	106	6	
	5340370	8-23-94	Cadien	51	38	
	5314843	5-24-94	Yu	437	225	
	5308438	5-3-94	Cote	156	636	
	5196353	3-23-93	Sandhu	437	7	
	5166080	11-24-92	Schietinger	437	7	
	5154512	10-13-92	Schietinger	374	9	
	5137544	8-11-92	Medillin	51	308	
	5107445	4-21-92	Jensen	36	525	
	5069002	12-3-91	Sandhu	51	165R	
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	"Intermetal Dielectric Cost-of-Ownership", Case, C.B. and Case, C. J., <u>Semiconductor International</u> , June 1995, pp 83-88
	"Using COO to select Nitride PECVD clean cycle", Anderson, Bob, et al., <u>Semiconductor International</u> , Oct. 1993, pp 86-88
	"The application of cost of ownership simulation to wafer sort and final test", Jimez, D. W. et al., SEMI's Manufacturing test Conference, July, 1993
	"Reducing Tungsten Deposition equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , Oct. 1992, pp 23-25
	"Reducing ion-implant equipment cost of ownship through in situ contamination prevention and control", Burghard, R. W., et al., <u>Microcontamination</u> , Sept. 1992, pp 27-30
	"Reducing tungsten-etch equipment cost of ownership through in sity contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , June 1992, pp 33-36
	"Reducing process equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , May. 1992, pp 21-24
	"Cost of ownership for inspection equipment", Dance D. and Bryson, P., Sematech, Austin, Texas, date unknown

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